



Docket No. 0008-FA-US

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re Application of Hunt et al.

Group Art No. 1762 (parent)

Application No. 09/748,714

Filed: 21 December 2000

For: CHEMICAL VAPOR DEPOSITION METHODS FOR MAKING  
POWDERS AND COATINGS, AND COATINGS MADE  
USING THESE METHODS

**Submission of Additional Fees—Large Entity Status**

Assistant Secretary and Commissioner of Patents and Trademarks  
Washington D.C. 20231

RECEIVED

JUN 4 2001

OFFICE OF PETITIONS

Sir:

Fees, as calculated by the NOTICE TO FILE MISSING PARTS OF  
NONPROVISIONAL APPLICATION dated 23 February 2001, of \$1241 were paid on a  
Small Entity basis.

It has subsequently been determined that Large Entity fees should have been paid.  
It is believed that the technology which is the subject matter of this application falls  
under a general technology license to a Large Entity.

Neither this application nor its parent case were specifically listed in the schedule  
of patents and application attached to the license agreement.

The erroneous claim of Small Entity status was made without deceptive intent.

The patent Office is authorized to charge an additional \$1241 for filing fees and  
surcharge to Deposit Account No. 501231. A duplicate copy of this letter is attached.

21 May, 2001

*Wayne E. Nacker*

Wayne E. Nacker, Reg. 29,571  
Customer No. 24948

I, Wayne E. Nacker, hereby certified that this document and the documents listed above were deposited with the U.S. Postal Service  
on 21 May, 2001, postage paid, addressed to the Assistant Commissioner for Patents, Washington, D.C.  
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05/01/2001 STEFFER 00000003 501231 09743714

01 000001	710.00	CH
02 000002	000.00	CH
03 000003	000.00	CH
04 000004	000.00	CH
05 000005	1241.00	CH

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